**Preliminary Amendment** 

Applicant: Thomas Hecht et al.

Serial No.: Unknown

(Priority Application No. DE 102 45 537.6)

(International Application No. PCT/DE03/03188)

Filed: Herewith

(Priority Date: September 30, 2002)

(International Filing Date: September 24, 2003)

Docket No.: I433.153.101/13.555

Title: METHOD AND PROCESS REACTOR FOR SEQUENTIAL GAS PHASE DEPOSITION BY MEANS

OF A PROCESS CHAMBER AND AN AUXILIARY CHAMBER (As Amended)

## IN THE TITLE

Please replace the title with the following rewritten title:

METHOD AND PROCESS REACTOR FOR SEQUENTIAL GAS PHASE DEPOSITION BY MEANS OF A PROCESS CHAMBER AND AN AUXILIARY **CHAMBER** 

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## IN THE SPECIFICATION

Please insert the following paragraph beginning at page 1, line 6, of the substitute specification with the following paragraph:

## **Cross Reference to Related Application**

This Utility Patent Application claims the benefit of the filing date of German Application No. DE 102 45 537.6, filed September 30, 2002, and International Application No. PCT/DE03/03188, filed September 24, 2003, both of which are herein incorporated by reference.